



Docket No.: P2002,0889

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By: 

Date: December 2, 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applic. No. : 10/686,848  
Applicant : Martin Rößiger et al.  
Filed : October 16, 2003  
Art Unit : to be assigned  
Examiner : to be assigned

Docket No. : P2002,0889  
Customer No. : 24131

INFORMATION DISCLOSURE STATEMENT

Hon. Commissioner for Patents

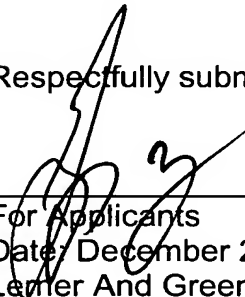
Sir:

In accordance with 37 C.F.R. 1.98 copies of the following patents and/or publications are submitted herewith:

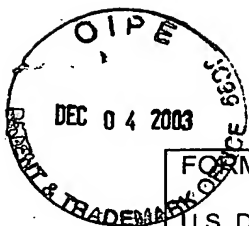
Jens Staecker et al.: "Advances in Process Overlay on 300 mm wafers", *SPIE Conference, March 3-8, 2002*;

Paul C. Hinnen et al.: "Advances in Process Overlay", *SPIE Conference, March 3-8, 2002*.

Respectfully submitted,

  
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FORM PTO-1449 (SUBSTITUTE)

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEINFORMATION DISCLOSURE  
STATEMENT BY APPLICANT  
(37 CFR 1.98(b))Attorney Docket No.:  
P2002,0889Applic. No.  
10/686,848

Applicant

Martin Rössiger et al.

Filing Date  
October 16, 2003

Group Art Unit

## U.S. PATENT DOCUMENTS

EXAMINER INITIALS		PATENT NO.	DATE	PATENTEE	CLASS	SUB CLASS	FILING DATE
	A						
	B						
	C						
	D						
	E						
	F						
	G						
	H						
	I						

## FOREIGN PATENT DOCUMENT

		DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANSL. YES   NO
	J						
	K						
	L						
	M						
	N						

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)

	O	Jens Staecker et al.: "Advances in Process Overlay on 300 mm wafers", <i>SPIE Conference, March 3-8, 2002</i> ;
	P	Paul C. Hinnen et al.: "Advances in Process Overlay", <i>SPIE Conference, March 3-8, 2002</i>

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.